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APPLICATION NO. FILING DATE		ING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.		
10/662,408	09	/16/2003	Takahiro Matsumoto	03560.003354.	1686		
5514	7590	01/12/2005		EXAM	EXAMINER		
		LA HARPER &	LAU, TUNG S				
30 ROCKEFELLER PLAZA NEW YORK, NY 10112				ART UNIT	PAPER NUMBER		
	•			2863			

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application	ı No.	Applicant(s)					
		10/662,408	10/662,408 MATSUMOTO E		AL.				
	Office Action Summary	Examiner		Art Unit					
		Tung S Lau		2863					
Period fo	The MAILING DATE of this communication ap	pears on the o	over sheet with the c	correspondence ac	ldress				
A SH THE - Exte after - If the - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REPL MAILING DATE OF THIS COMMUNICATION. nsions of time may be available under the provisions of 37 CFR 1. SIX (6) MONTHS from the mailing date of this communication. a period for reply specified above is less than thirty (30) days, a reply period for reply is specified above, the maximum statutory period are to reply within the set or extended period for reply will, by statut reply received by the Office later than three months after the mailined patent term adjustment. See 37 CFR 1.704(b).	136(a). In no event ply within the statuto I will apply and will o te, cause the applic	t, however, may a reply be tir ory minimum of thirty (30) day expire SIX (6) MONTHS from ation to become ABANDONE	nely filed s will be considered time the mailing date of this c (D) (35 U.S.C. § 133).					
Status									
1)⊠ 2a)⊠ 3)□	This action is FINAL. 2b) This action is non-final.								
Disposit	ion of Claims								
5)	<u> </u>								
Applicat	ion Papers								
10)	The specification is objected to by the Examin The drawing(s) filed on is/are: a) ac Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Examin Theorem 1.	cepted or b) e drawing(s) be ction is required	held in abeyance. Se	e 37 CFR 1.85(a). ojected to. See 37 C	• •				
Priority (under 35 U.S.C. § 119								
12)□ a)	Acknowledgment is made of a claim for foreig All b) Some * c) None of: 1. Certified copies of the priority documer 2. Certified copies of the priority documer 3. Copies of the certified copies of the priority application from the International Burea See the attached detailed Office action for a lis	nts have been nts have been ority documer au (PCT Rule	received. received in Applicatets have been received 17.2(a)).	ion No ed in this National	Stage				
2) Notice 3) Infor	ot(s) Dee of References Cited (PTO-892) Dee of Draftsperson's Patent Drawing Review (PTO-948) Mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08 Der No(s)/Mail Date	3)	4) Interview Summary Paper No(s)/Mail D 5) Notice of Informal F 6) Other:	ate	O-152)				

DETAILED ACTION

1. The Amendments to the specification on 12-14-2004 were accepted by the examiner.

Claim Rejections - 35 USC § 102

- 2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:
 - A person shall be entitled to a patent unless –
 - (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
 - Claims 9-17 are rejected under 35 U.S.C. 102(b) as being anticipated by Kawakubo (U.S. Patent 5,760,411).

Regarding claim 9:

Kawakubo discloses a position detection method of detecting a position of a mark, said method comprising steps of: detecting light from the mark under a first detecting condition to obtain a position of the mark as a first position (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46); detecting light from the mark under a second detecting condition different from the first detecting condition to obtain a position of the mark as a second position (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46); obtaining offset data for offsetting one of the first and second positions based on previously prepared information for relating the first and second positions to the offset data (Col. 8-9, Lines 57-44); and detecting a position of the mark based on the offset data and one of the first and second positions (Col. 8-9, Lines 57-44).

Regarding claim 16:

Kawakubo discloses an exposure apparatus for transferring a pattern to a workpiece, said apparatus comprising: means for detecting light from a mark on the workpiece under a first detecting condition to obtain a position of the mark as a first position (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46); means for detecting light from the mark under a second detecting condition different from the first detecting condition to obtain a position of the mark as a second position (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46), means for obtaining offset data for offsetting one of the first and second positions based on previously prepared information for relating the first and second positions to the offset data (Col. 8-9, Lines 57-44); means for detecting a position of the mark based on the offset data and one of the first and second positions (Col. 8-9, Lines 57-44); and means for aligning the workpiece based on the position of the mark detected by said position detecting means (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46, abstract). Regarding claim 10, Kawakubo discloses detecting conditions differ from each other in focus state of an image of the mark (fig. 2, unit PL, fig. 2, fig. 3); Regarding claim 11, Kawakubo discloses detecting conditions differ from each other in a coherence factor of an illumination optical system for illuminating the mark (fig. 2, 3); Regarding claim 12, Kawakubo discloses different condition differ in numerical aperture (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46); Regarding claim 13, Kawakubo discloses different condition differ in polarization and wavelength (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46); Regarding claim 14, Kawakubo discloses previously prepared information relates a difference between the first

and second positions to the offset data (Col. 8-9, Lines 57-44); Regarding claim 15, Kawakubo discloses previously prepared information is a coefficient multiplied to the difference, and one of the first and second position is offset by a product of the coefficient and the difference to detect the position of the mark (Col. 8-9, Lines 57-44); Regarding claim 17, Kawakubo discloses developing the workpiece to which the pattern has been transferred (Col. 8-9, Lines 57-44, fig. 2, 3).

Response to Arguments

 Applicant's arguments filed 12/14/2004 have been fully considered but they are not persuasive.

A. Applicant argues in the arguments that the prior art does not show the 'offset data for offsetting one of a first mark position detected under a first light detecting condition and a second mark position detected under a second light detecting condition is obtained based on previously prepared information relating the first and second positions to the offset data and another feature that the mark position is detected based on the offset data and one of the first and second positions'. Kawakubo discloses 'offset data for offsetting one of a first mark position detected under a first light detecting condition and a second mark position detected under a second light detecting condition is obtained based on previously prepared information relating the first and second positions to the offset data and another feature that the mark position is detected based on the

offset data and one of the first and second positions' in Col. 8-9, Lines 57-44, fig. 2, 3.

B. Applicant continues to argue in the arguments that the prior art does not show the detail in claims 10 –15 and 17. Regarding claim 10, Kawakubo discloses detecting conditions differ from each other in focus state of an image of the mark (fig. 2, unit PL, fig. 2, fig. 3); Regarding claim 11, Kawakubo discloses detecting conditions differ from each other in a coherence factor of an illumination optical system for illuminating the mark (fig. 2, 3); Regarding claim 12, Kawakubo discloses different condition differ in numerical aperture (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46); Regarding claim 13, Kawakubo discloses different condition differ in polarization and wavelength (Col. 1-2, Lines 46-40, Col. 7, Lines 8-46); Regarding claim 14, Kawakubo discloses previously prepared information relates a difference between the first and second positions to the offset data (Col. 8-9, Lines 57-44); Regarding claim 15, Kawakubo discloses previously prepared information is a coefficient multiplied to the difference, and one of the first and second position is offset by a product of the coefficient and the difference to detect the position of the mark (Col. 8-9, Lines 57-44); Regarding claim 17, Kawakubo discloses developing the workpiece to which the pattern has been transferred (Col. 8-9, Lines 57-44, fig. 2, 3).

Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Tung S Lau whose telephone number is 571-272-2274. The examiner can normally be reached on M-F 9-5:30. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John Barlow can be reached on 571-272-2269. The fax phone numbers for the organization where this application or proceeding is assigned is 703-872-9306

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 TL

John Barlow
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Technology Center 2800